

## CHEMICAL LIQUID SUPPLY APPARATUS

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**Classification:**

- **international:** *B01J4/00; H01L21/027; H01L21/30; H01L21/304; H01L21/306; B01J4/00; H01L21/02; (IPC1-7): B01J4/00; H01L21/30; H01L21/304; H01L21/306*

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### Abstract of JP 63252538 (A)

**PURPOSE:** To simplify a pressurizing means and to facilitate the replacement of a chemical liquid tank, by pressurizing a hermetically closed container having a plurality of chemical liquid tanks arranged therein to bring the chemical liquid tanks to a pressurized state all at once and selectively releasing valves to individually supplying chemical liquids. **CONSTITUTION:** When chemical liquids are supplied from chemical liquid tank 2a-2c, for example, the chemical liquid tank 2a is selected to open a valve 6 and nitrogen gas is introduced into the chemical liquid tank 2a from a gas supply pipe 5 under pressure to pressurize the interior of said tank 2a. Subsequently, a valve 4a is opened to supply only a necessary amount of the chemical liquid to a predetermined area from the chemical liquid tank 2a through a conduit 3a by gas pressure. When the chemical liquid tank 2a becomes empty, a detection means detects this state to close the valve 4a to stop the supply of the chemical liquid and to close the valve 6. Subsequently, either one of the remaining chemical liquid tanks is selected to similarly supply the chemical liquid and the supply of the chemical liquids is performed until all of the chemical liquid tanks 2a-2c become empty.

